



A. Interconnect & Package 분과

2021년 1월 27일(수), 13:00-14:30 / 채널 C

[WC3-A] Emerging Interconnect I

좌장: 김병준 교수 (안동대학교), 최두호 교수 (동의대학교)

<p>WC3-A-1 13:00-13:30</p>	<p>[초청] New Materials and Processes for Interconnect Scaling, and Beyond the Scaling Limit Sang Hoon Ahn, Woojin Lee, Iksoo Kim, Kihyun Hwang <i>Foundry Process Development Team, Samsung Electronics Co., Ltd.</i></p>
<p>WC3-A-2 13:30-14:00</p>	<p>[초청] Suppression of Volmer-Weber Metallic Growth via Surface Modification of Oxide Substrate for the Applications in Transparent Electrodes and Transparent Heaters Dooho Choi <i>Advanced Materials Engineering, Dong-Eui University</i></p>
<p>WC3-A-3 14:00-14:15</p>	<p>DC Magnetron Sputter 방식으로 증착한 비정질 탄소막의 내에칭 특성연구 Sungtae Kim, Cheol Kim, Seung-Hyun Oh, and Young-Chang Joo <i>Department of Materials Science Engineering, Seoul National University</i></p>
<p>WC3-A-4 14:15-14:30</p>	<p>Co-sputtered CoAl Thin Films as an Alternative Material for VLSI Interconnects Kyeong-Youn Song¹ and Hoo-Jeong Lee^{1,2} ¹<i>SKKU Advanced Institute of Nano Technology (SAINT), Sungkyunkwan University,</i> ²<i>School of Advanced Materials Science and Engineering, Sungkyunkwan University</i></p>